

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1904		PRIORITY SERIAL NO. 09/843,116	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Michael Nuttall et al.		PRIORITY FILING DATE April 24, 2001	
				PRIORITY GROUP 2813			
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	4,497,683	02/1985	Celler et al.	156	603	
	AB	4,963,506	10/1990	Liaw et al.	438	482	
	AC	5,080,933	01/1992	Gruppen-Semansky et al.	427	255.1	
	AD	5,110,757	05/1992	Arst et al.	438	489	
	AE	5,124,276	06/1992	Samata et al.	438	607	
	AF	5,364,815	11/1994	Osada	438	489	
	AG	5,441,012	08/1995	Aketagawa et al.	117	86	
	AH	5,006,911	04/1991	Sivan	357	23.11	
	AI	5,818,100	10/1998	Grider et al.	257	616	
	AJ	5,037,775	08/1991	Reisman	437	89	
	AK	5,646,073	07/1997	Grider et al.	437	233	
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AL						
	AM						
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR	Violette, Katherine E., et al., "Low Temperature Selective Silicon Epitaxy by Ultra High Vacuum Rapid Thermal Chemical Vapor Deposition Using Si <sub>3</sub> H <sub>8</sub> , H <sub>2</sub> , and Cl <sub>2</sub> ", Appl. Phys. Lett., Vol. 68(1), pp. 66-68 (January 1996).					
	AS	Wolf, Stanley, et al., "Chemical Vapor Deposition of Amorphous and Polycrystalline Films, Silicon Processing for the VLSI Era", Vol. 1: Process Technology, pp. 183 and 191 (Lattice Press).					
	AT	References can't be found in the parent case, 09/843,116. Applicant needed to provide these references.					
EXAMINER				DATE CONSIDERED			
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							

 1000 U.S. PTO  
10/050426

01/15/02

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1904		PRIORITY SERIAL NO. 09/843,116	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Michael Nuttall et al.			
				PRIORITY FILING DATE April 24, 2001		PRIORITY GROUP 2813	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,013,575	01/2000	Itoh	438	641	
	AB	4,948,755	08/1990	Mo	437	195	
	AC	4,966,868	10/1990	Murali et al.	437	193	
	AD	5,607,878	03/1997	Otsuka et al.	437	187	
	AE	5,663,098	09/1997	Creighton et al.	438	675	
	AF	6,017,823	01/2000	Onishiguchi et al.	438	696	
	AG	6,069,036	05/2000	Kim	438	238	
	AH	5,798,278	08/1998	Chan et al.	437	43	
	AI	5,037,778	08/06/91	Reisman	437	89	
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes    No
	AL						
	AM						
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR						
	AS						
	AT						
EXAMINER				DATE CONSIDERED			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1904		SERIAL NO. 10/050,426	
<div style="position: relative; height: 100px;"> <div style="position: absolute; top: 0; left: 0; width: 100%; height: 100%; border: 1px solid black; border-radius: 50%; text-align: center; color: black; font-weight: bold; font-size: 1.2em;"> O I P E APR 25 2003 PATENT &amp; TRADEMARK OFFICE </div> </div>				LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)			
				APPLICANT: Michael Nuttall et al.			
				FILING DATE January 15, 2002		GROUP 2813	
U.S. PATENT DOCUMENTS							
*Examiner's Initials	AA	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AJ						
	AK						
	AL						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
/	AM		Wolf, Stanley, "Silicon Processing for the VLSI Era", Vol. 2: Process Integration, pg. 45 (Lattice Press)				
	AN						
	AO						
EXAMINER		DATE CONSIDERED					
Sarkis		7/10/03					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							



RECEIVED  
APR 29 2003  
TECHNOLOGY CENTER 2000

LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)

MAY 07 2002

APPLICANT  
Michael NuttallFILING DATE  
January 15, 2002GROUP  
2813

## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,118,639	06/1992	Roth et al.	437/	41	
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		
	AS		
	AT		

EXAMINER



DATE CONSIDERED

7/11/03

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

RECEIVED  
MAY 13 2002  
TO 2800 MAIL ROOM